



<b>Session Title:</b>	<b>[WeD1] Lithography Process I</b>
<b>Session Date:</b>	<b>November 13 (Wed.), 2024</b>
<b>Session Time:</b>	<b>09:00-10:45</b>
<b>Session Room:</b>	<b>Room D (Sidney Room, 2F, Paradise Hotel Busan)</b>
<b>Session Chair:</b>	<b>Prof. Chawon Koh (Yonsei Univ., Korea)</b>

**[WeD1-1] [Invited] - Online**

**09:00-09:45**

**EUV Lithography – Latest Progress and Outlook**

**Anthony Yen (ASML, USA)**

**[WeD1-2] [Invited]**

**09:45-10:15**

**Advanced Lithography Technology Materials towards Next Generation; Challenges and Opportunities**

**Toru Kimura (JSR Corp., Japan)**